



09/816,603

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:	Mark L. Jenson	Examiner:	R. Alejandro
Serial No.:	09/816,603	Group Art Unit:	1745
Filed:	March 23, 2001	Docket:	1327.009US1
Title:	CONTINUOUS PROCESSING OF THIN-FILM BATTERIES AND LIKE DEVICES		

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RESPONSE TO RESTRICTION REQUIREMENT

Commissioner for Patents
Washington, D.C. 20231

In response to the Restriction Requirement mailed November 5, 2002, Applicant elects, without traverse, Group 2 (claims 11-31), drawn to a system for making a thin-film device. Applicant reserves the right to reintroduce claims 1-10 in one or more divisional applications at a later date.

In the Claims

Please substitute the claim set in the appendix entitled Clean Version of Pending Claims for the previously pending claim set. The substitute claim set is intended to reflect cancellation of claims 1-10, amendment of previously pending claims 11, 22-31, and addition of new claims 32-41. The specific amendments to individual claims are detailed in the following marked up set of claims.

11. [Amended Once] A system for making a thin-film device, the system comprising:
 a first substrate-supply station that supplies a substrate having a major surface area, the substrate having a first layer, having a composition different than the substrate, formed on a first surface area of the substrate's major surface area;
 a first deposition station that deposits a second layer onto the first layer, wherein the first deposition station supplies an amount of ion-assist energy to the second layer to aid in crystalline layer formation while controlling a stoichiometry of the crystalline layer without substantially heating the substrate.

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